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(71) Applicant (for all designated States except US):
SHOCKING TECHNOLOGIES, INC. [US/US]; 5870
Hellyer Avenue, San Jose, California 95138 (US).

(72) Inventor; and

(75) Inventor/Applicant (for US only): **KOSOWSKY, Lex**
[US/US]; Shocking Technologies, Inc., 5870 Hellyer Av-
enue, San Jose, California 95138 (US).

(74) Agents: **KLINE, Keith** et al.; Carr & Ferrell LLP, 120
Constitution Drive, Menlo Park, California 94025 (US).

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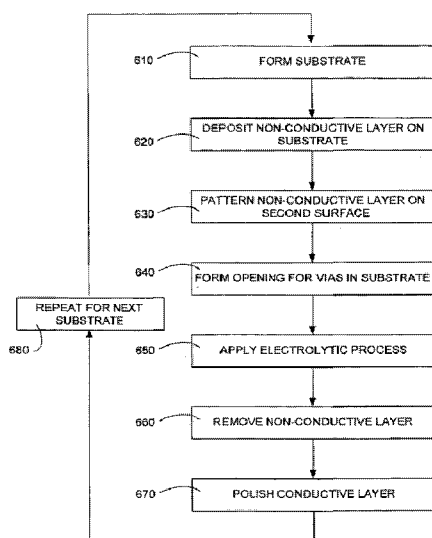
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(54) Title: METAL DEPOSITION

Figure 8



(57) Abstract: Systems and methods include depositing one or more ma-
terials on a voltage switchable dielectric material. In certain aspects, a
voltage switchable dielectric material is disposed on a conductive back-
plane. In some embodiments, a voltage switchable dielectric material in-
cludes regions having different characteristic voltages associated with de-
position thereon. Some embodiments include masking, and may include
the use of a removable contact mask. Certain embodiments include elec-
trografting. Some embodiments include an intermediate layer disposed be-
tween two layers.